



# High purity LPE GaAs for far infrared blocked impurity band detectors

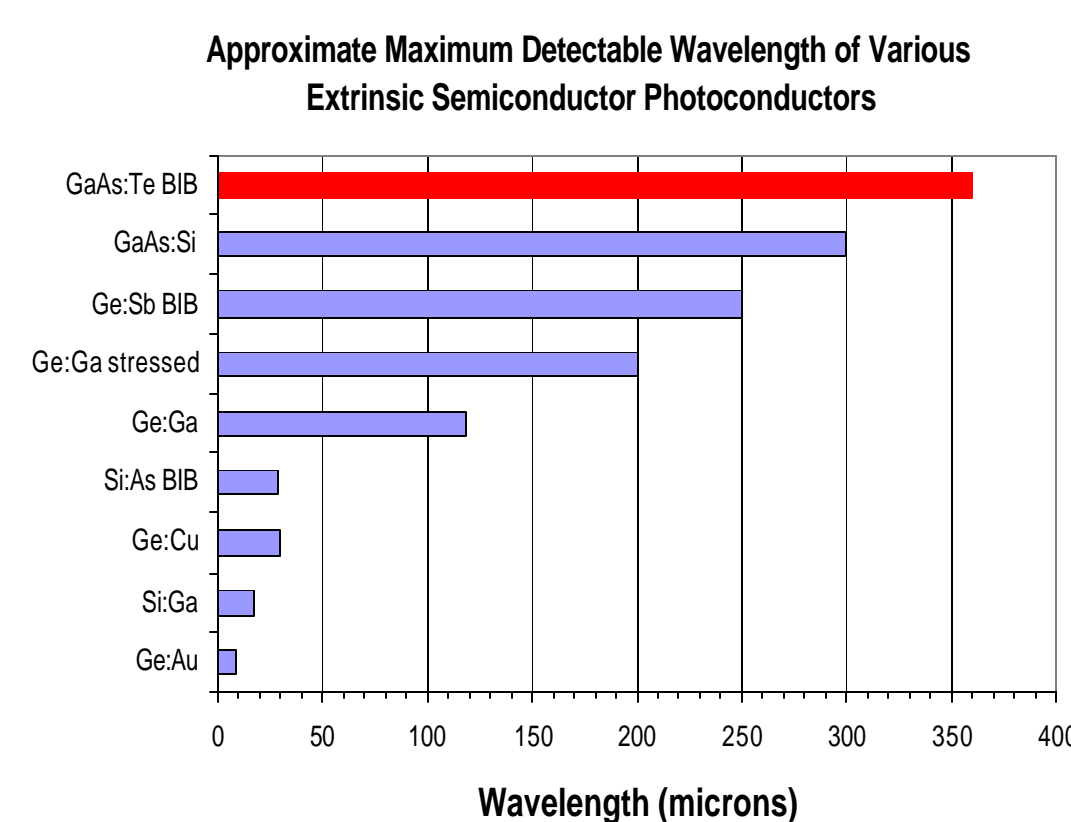


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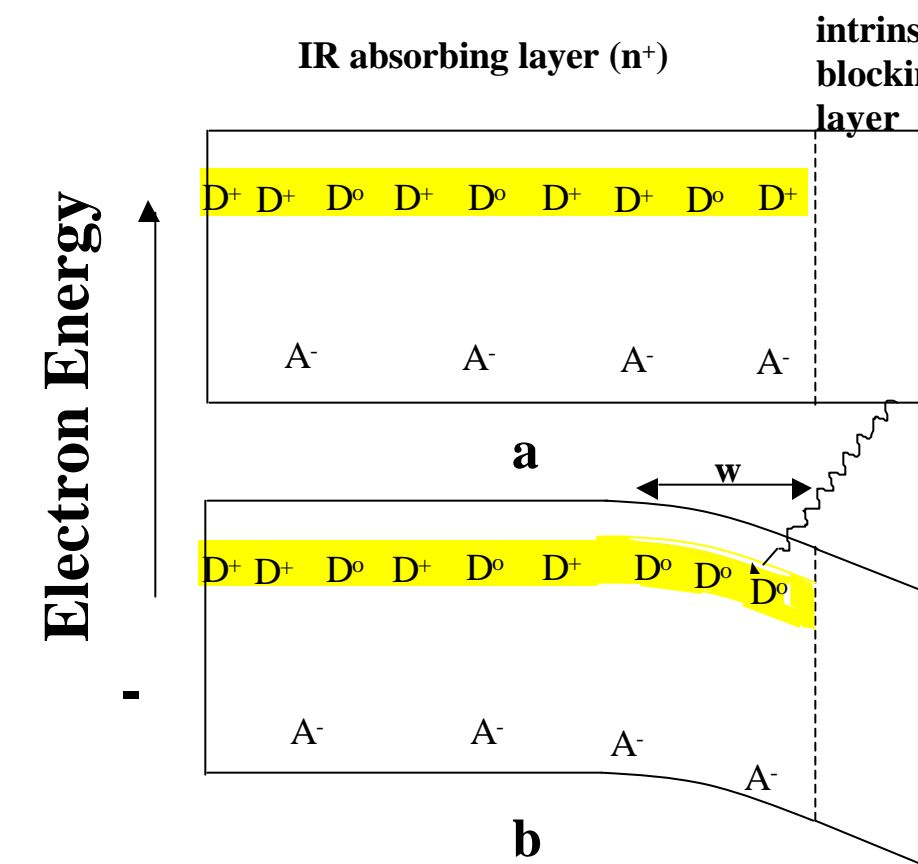
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## Photoconductive Devices - Current technology and future trends



- High efficiency, low noise photoconductors that can detect light beyond 200 $\mu$ m are currently not available.
- GaAs detectors can extend the long wavelength cutoff beyond stressed Ge:Ga because of the small shallow donor ionization energy ( $\sim 6$ meV)

## BIB Detector Design and Operation



Energy band diagram of a BIB detector: a) unbiased b) with an applied bias

- Photon absorption in n+ region.
- Photo-ionized free carriers transport in the conduction band, through the blocking layer into the contact.
- D<sup>+</sup> move toward the negative contact.
- Electrons in the donor band cannot pass through the blocking layer since no such band exists there.

## Requirements for Efficient BIB Operation

- The blocking layer should be as pure as possible ( $N_d - N_a \leq 10^{11}$  to  $10^{12}$  cm<sup>-3</sup>) to minimize the possibility of electron trapping at an ionized donor or deep level and to maintain a high and uniform electric field across the region.
- The absorbing layer should be highly doped ( $N_d \approx 10^{15}$  cm<sup>-3</sup>) but have very low compensating (minority) impurity concentration in order to maximize the depletion region thickness.

$$\text{depletion region thickness } w = \sqrt{\frac{2\epsilon\epsilon_0(V_a - V_{bi})}{eN_{\text{minority}}} + b^2} - b$$

b=blocking layer thickness

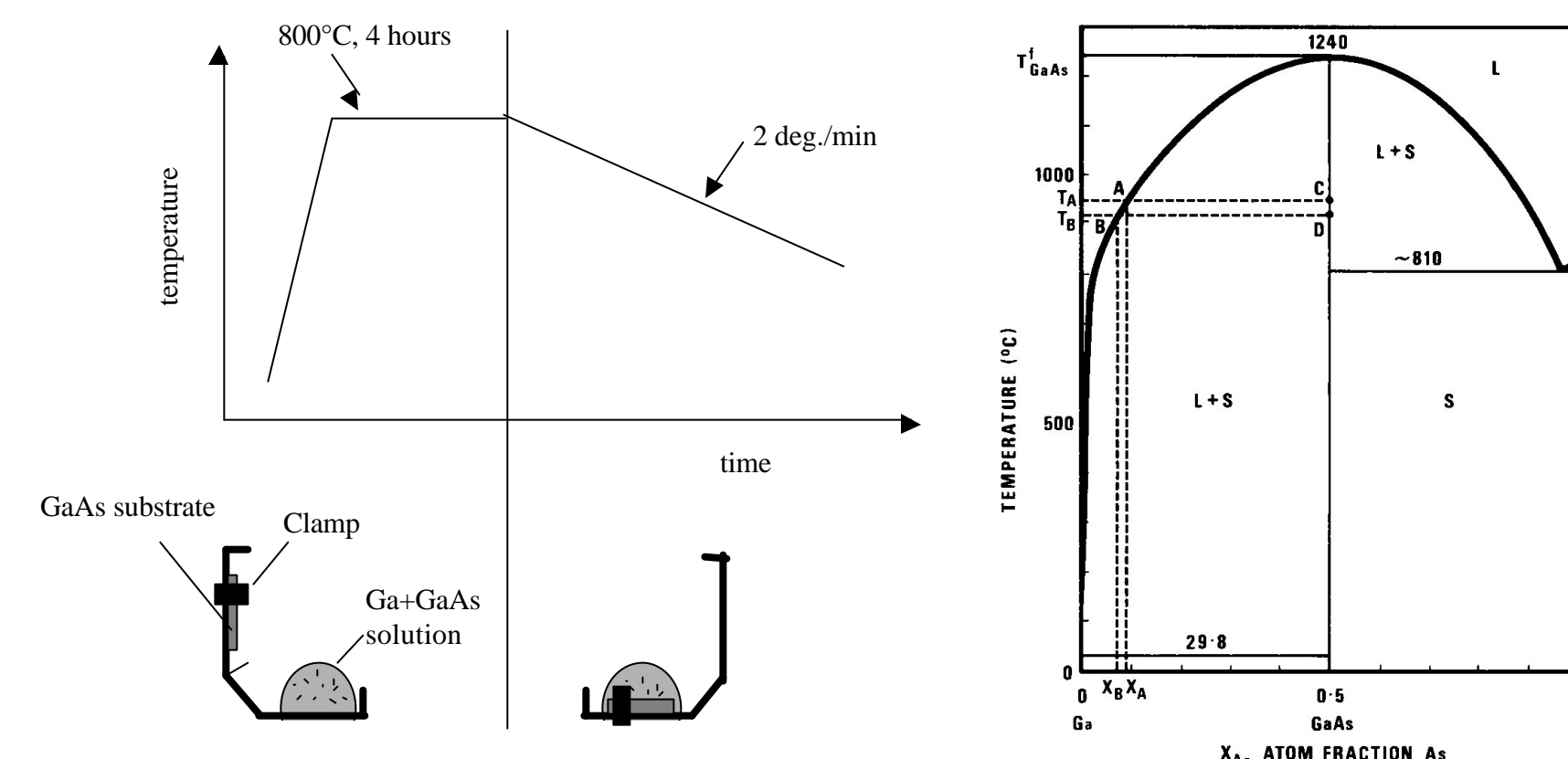
## Predicted single pass BIB absorption versus minority doping concentration

$N_d = 1 \times 10^{15}$  cm<sup>-3</sup>,  $\alpha = 125$  cm<sup>-1</sup>,  $b = 5$   $\mu$ m

$N_a$ (cm <sup>-3</sup> )	Bias (V)	w (mm)	Percent Absorption
$1 \times 10^{13}$	1.5	10	12
$5 \times 10^{12}$	1.5	16	18
$1 \times 10^{12}$	1.5	41	40
$7 \times 10^{11}$	1.5	50	46
$5 \times 10^{11}$	1.5	60	53

\* Bosonworth, Crandall, Enstrom, 1968

## Liquid Phase Epitaxy of GaAs – growth of the blocking layer



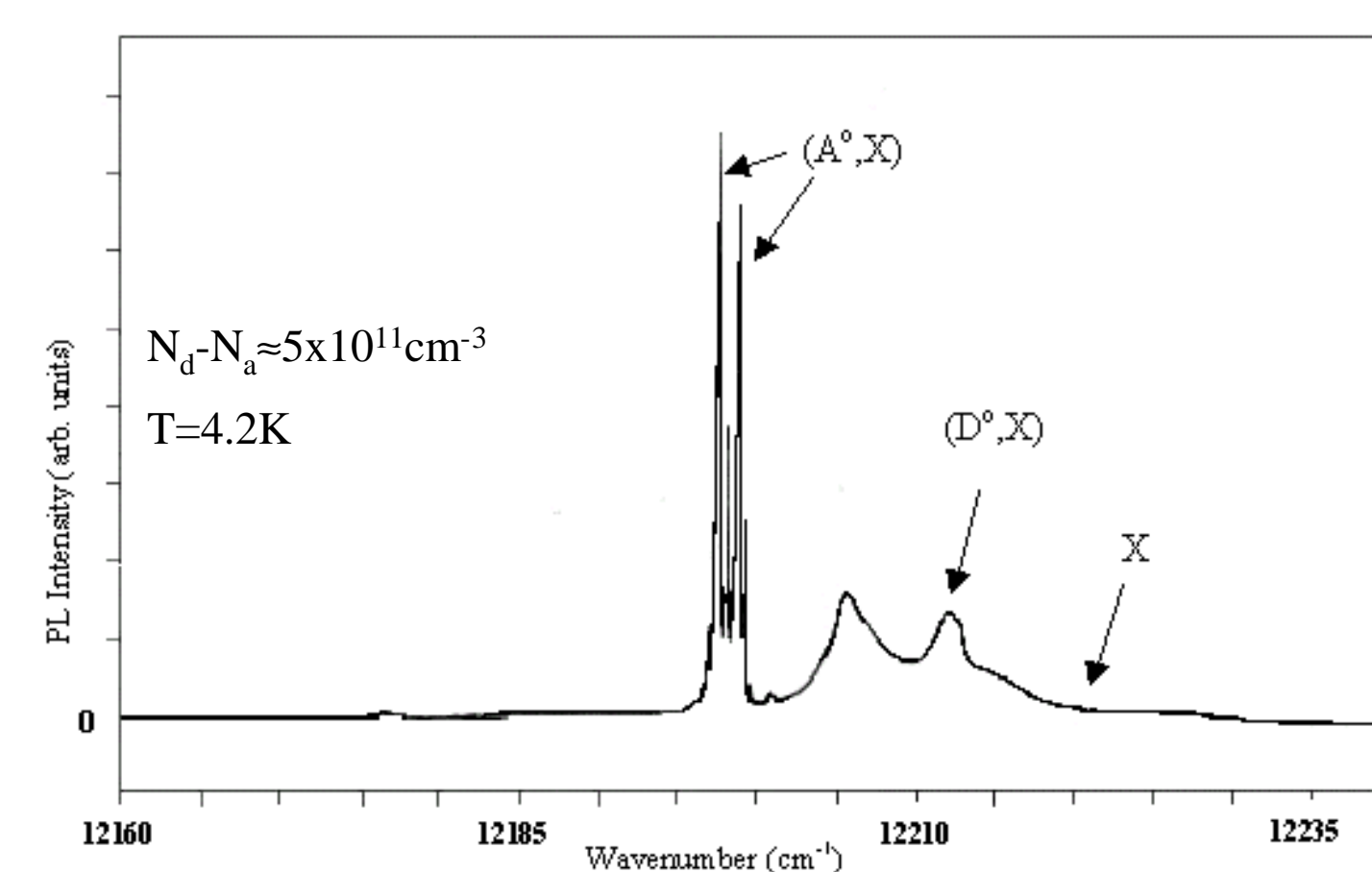
- The purity of LPE GaAs films is a result of the segregation of impurities into the liquid phase during growth, as in bulk semiconductor growth, and the availability of very high purity Ga solvent material (99.99999%).

## Blocking layer characterization

- **Hall effect and resistivity** measurements determine the net impurity concentration and carrier mobility.
  - $|N_d - N_a| = 2 \times 10^{12}$  cm<sup>-3</sup>  $\mu_{77} = 180,000$  cm<sup>2</sup>/V-s
- **Capacitance-Voltage** measurements determine the net space charge
  - $|N_d - N_a| = 5 \times 10^{11}$  cm<sup>-3</sup>
- **Photoluminescence** can be used to identify individual acceptor species.
  - Major acceptor: C
- **Magneto-photoluminescence** (courtesy of M. Thewalt, Simon Fraser University) can be used to identify individual donor species.
  - Major donors: S, Si

## Photoluminescence of shallow dopants in an ultra-high purity GaAs film

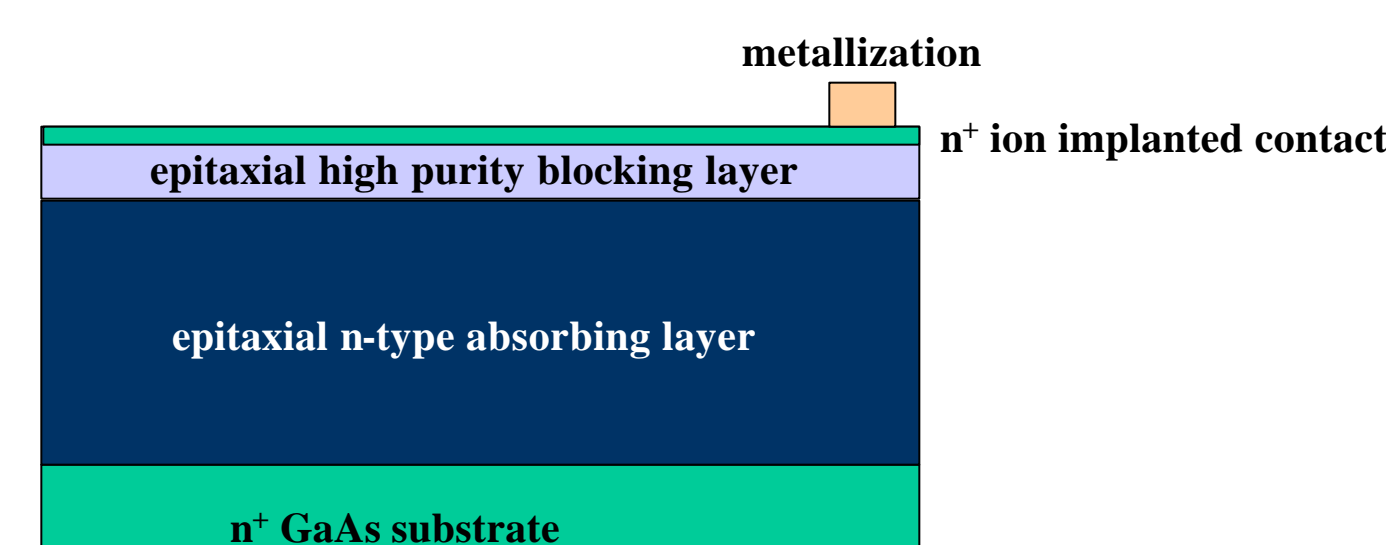
Extremely sharp luminescence lines and presence of the free exciton peak confirm the very high purity of the film



Photoluminescence spectrum of GaAs epilayer 21151

## Future Work - BIB Production

Once the ability to grow highly doped, low compensation absorbing layers has been developed, it will be combined with a high purity blocking layer to produce a BIB



## Acknowledgements

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